



EMICON SA



PLASMA MONITOR AND
PROCESS CONTROL SYSTEM



STAND-ALONE SPECTROSCOPIC PLASMA MONITOR SYSTEM FOR INDUSTRIAL PRODUCTION LINES

Highlight Features:

- Up to 8 spectrometer units for data acquisition at different machine locations
- Input of up to 8 external voltage signals (e.g. from lambda probe, target voltage,...)
- Stand-alone operation by means of integrated processor unit
- Integrated touch panel display for on-site information and settings
- Communication by industrial standard interfaces (LAN, Profibus, IOs, ...)

Your Benefits:

- Upgrade your production line for increasing product quality or producing high-end products
- Stabilize process by simultaneous PID control e.g. of gas flow control and target voltage
- Control and compensate target erosion in sputter applications
- Retrofit your existing PEM for enhanced productivity
- Integrate as stand-alone system in machine control